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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| In re Patent Application of: |) | |
| Mitsuhiro ICHIJO et al. |) | Confirmation No. 7738 |
| Application No. 10/804,053 |) | Examiner: Long Pham |
| Filed: March 19, 2004 |) | Group Art Unit: 2814 |
| For: FILM FORMATION METHOD AND |) | |
| MANUFACTURING METHOD OF |) | Date: October 26, 2007 |
| SEMICONDUCTOR DEVICE |) | |

AMENDMENT AFTER FINAL

MAIL STOP RCE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the final Office Action mailed August 3, 2007, Applicants respectfully request reconsideration and allowance of the above-identified application in view of the following amendments and remarks.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 14 of this paper.